

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT
PTO FORM 1449**

Atty. Docket No.
10537/132

Serial No. **09/868447**
To be assigned

Applicant(s)
STOLLE et al.

Filing Date
Herewith **6/18/01**

Group Art Unit
To be assigned **1762**

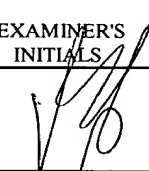
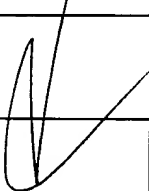
U. S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NUMBER	PATENT DATE	NAME	CLASS	SUBCLASS	FILING DATE

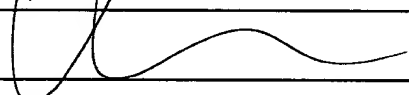
FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION	
						YES	NO

OTHER DOCUMENTS

EXAMINER'S INITIALS	AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.
	Kim, et al., "Deposition and Structural Characterization of ZR02 and YTTRIA-Stabilized ZR02 Films by Chemical Vapor Deposition", Thin Solid Films, CH, Elsevier-Sequoia S.A. Lausanne, Bd. 254, Nr. 1/02, 1 January 1995, pp. 33-38. *
	Cao, et al., "Research on YSZ Thin Films Prepared by Plasma-CVD Process" Thin Solid Films, CH, Elsevier-Sequoia S.A. Lausanne, Bd. 249, No. 2, 15 September 1994, pp. 163-167. *
	Masanobu, et al., Preparation of ZR02-Y203 Films by CVD Using B-Diketone Metal Chelates", Journal of the Ceramic Society of Japan, International Edition, JP, Fuji Technology Press, Tokyo, Bd. 101, Nr. 3, 1 March 1993, pp. 283-286. *
	Bertrand, et al., "Zirconia coatings realized by microwave plasma-enhanced chemical vapor deposition", Thin Solid Films, CH, Elsevier-Sequoia S.A. Lausanne, Bd. 292, Nr. 1, 5 January 1997, pp. 241-246. *

* - Copy of reference is not enclosed because reference is cited in International Search Report (copy of reference provided by International Searching Authority).

EXAMINER 	DATE CONSIDERED 6/25/03
EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	